

**BEST AVAILABLE COPY****Amendment to Claims**

This listing of Claims will replace all prior versions and listings of claims in this Application.

**Listing of Claims**

**Claim 1. (CURRENTLY AMENDED)** A memory array layer for use in a 3D RRAM comprising, on a silicon substrate having peripheral circuitry thereon:

- a first layer of silicon oxide, deposited and planarized;
- a bottom electrode formed of a material taken from the group of materials consisting of Pt, PtRhO<sub>x</sub>, PtIrO<sub>x</sub> and TiN/Pt;
- a second oxide layer having a thickness of at least 1.5X that of the thickness of the bottom electrode, deposited and ~~planarized~~ planarized to a level where at the bottom electrode is exposed;
- a layer of memory resistor material;
- a layer of Si<sub>3</sub>N<sub>4</sub>;
- a third oxide layer having a thickness of about 1.5X of that of the memory resistor material; CMPd to expose the memory resistor surface;
- a top electrode formed of a material taken from the group of materials consisting of Pt, PtRhO<sub>x</sub>, PtIrO<sub>x</sub> and TiN/Pt; and
- a covering oxide layer.

**Claim 2. (ORIGINAL)** The memory array layer of claim 1 wherein said first layer of silicon oxide has a thickness of between about 100 nm to 1000 nm; wherein said memory resistor material has a thickness of between about 20 nm to 150 nm; said Si<sub>3</sub>N<sub>4</sub> layer has a thickness of between about 10 nm to 30 nm; and wherein said third oxide layer has a thickness of

Page 3 Response to Office Action under 37 C.F.R. § 1.111 for Serial No. 10/720,890

**BEST AVAILABLE COPY**

about 1.5X of that of the memory resistor material.

**Claim 3. (ORIGINAL)** The memory array layer of claim 1 wherein said bottom electrode and said top electrode have, for an electrode taken from the group of electrodes formed of Pt, PtRhO<sub>x</sub>, and PtIrO<sub>x</sub>, a thickness of between about 50 nm to 300 nm, or for a bi-layer TiN/Pt, a thickness of between about 10nm to 200nm of TiN and between about 10 nm to 100 nm of Pt.

**Claim 4. (WITHDRAWN)** A method of programming a 3D RRAM comprising:

- selecting a memory cell to be written to;
- applying a high voltage programming pulse to a first related bit line;
- applying a low voltage programming pulse to a second related bit line;
- floating the associated word line;
- Biasing all other word lines with half-programming pulse voltages; and
- biasing all non-selected bit lines to the ground potential.

**Claim 5. (WITHDRAWN)** The method of claim 4 wherein reading a memory cell includes

- applying a small voltage to the word lines of the non-selected bits to enhance the line voltage difference between the first related bit line and the second related bit line; and
- applying a read voltage to the word line associated with the selected memory cell and detecting the voltage difference between the first related bit line and the second related bit line.

Page 4 Response to Office Action under 37 C.F.R. § 1.111 for Serial No. 10/720,890

**BEST AVAILABLE COPY**

**Claim 6. (WITHDRAWN)** A method of programming a 3D RRAM comprising:

- selecting a memory cell to be written to;
- applying a low voltage programming pulse to a first memory resistor in the memory cell;
- applying a high voltage programming pulse to a second memory resistor in the memory cell;
- setting the selected word line to ground potential;
- biasing all other word lines are biased to  $0.5 V_p$ ;
- biasing a first related bit line with a negative programming pulse, having a pulse amplitude of  $-V_p$ ;
- biasing a second related bit line with a positive programming pulse, having amplitude of  $+V_p$ ; and
- pulsing all non-selected memory resistors with a programming voltage of between  $0V_p$  and  $0.5 V_p$ .

**Claim 7. (WITHDRAWN)** The method of claim 4 wherein reading a memory cell includes

- applying a small voltage to the non-selected word lines to enhance the line voltage difference between the first related bit line and the second related bit line; and
- applying a read voltage to the word line associated with the selected memory cell and detecting the voltage difference between the first related bit line and the second related bit line.

Page 5 Response to Office Action under 37 C.F.R. § 1.111 for Serial No. 10/720,890